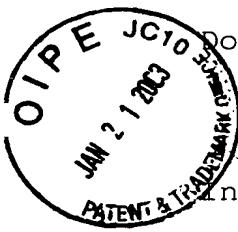


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Docket No. 216-028B

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: KATSIR, D. ET AL.  
Serial No. 09/893,914  
Filed June 28, 2001  
For METHOD FOR PRODUCING HIGH SURFACE  
AREA FOIL ELECTRODES  
Art Unit 1775  
Examiner Stein, Stephen J.

New York, New York 10036  
January 17, 2003

Commissioner for Patents  
Washington D.C. 20231

AMENDMENT

This Amendment is being filed in response to the Office Action that was mailed September 17, 2002. Kindly amend the subject application as follows:

IN THE CLAIMS

Kindly amend claims 29 and 34 as follows:

Kindly amend 29 and 34 to read as follows:

29. (Twice Amended) An article of manufacture having a vacuum deposited fractal surficial structure, which fractal surficial structure includes both valve metal and an oxide thereof, the valve metal being selected from the group consisting of aluminum, titanium, tantalum, niobium, zirconium, silicon, thorium, cadmium and tungsten.